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50. The method according to claim 39 wherein said second and third gate electrodes are formed by patterning a conductive layer, said conductive layer comprising a material selected from the group consisting of tantalum, chromium, titanium, tungsten, molybdenum, and silicon.--

## **REMARKS**

The Official Action of August 26, 2002 was received and its contents carefully reviewed. In response, Applicants hereby elect without traverse Group II (claims 31 and 32) drawn to a process for making a semiconductor device classified in Class 438, subclass 1+, and cancel non-elected claims 17-30...

Consideration and allowance of the instant application are now respectfully requested.

Respectfully submitted,

Jeffrey L. Costellia

Registration No. 35,483

NIXON PEABODY LLP 8180 Greensboro Drive, Suite 800 McLean, Virginia 22102 (703) 770-9300 (703) 770-9400 FAX